



Docket No. 740819-000442

Serial No.: 09/692,211

Page 1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of )

Akihiko ISHIBASHI et al. )

Serial No. 09/692,211 )

Filed: October 20, 2000 )

For: METHOD OF FABRICATING )  
NITRIDE SEMICONDUCTOR DEVICE )

Art Unit: 2812

Examiner: S. MULPURI

#10 Amended  
(NE)  
JH  
6/11/02

TS  
7-17

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to Commissioner for Patents, Washington, DC 20231 on May 13, 2002.

Deborah T. Tomme  
Deborah T. Tomme

AMENDMENT UNDER 37 C.F.R. 1.116

BOX AF

Commissioner for Patents  
Washington, D.C. 20231

Sir:

The following is presented in response to the Office Action mailed February 12, 2002, in connection with the above-captioned patent application.

IN THE CLAIMS:

Please cancel claims 1, 2, 3, 9 and 12.

Please amend claims 4-8 as follows.

4. (Amended) The method of fabricating a nitride semiconductor device of claim 13, wherein said second growth ambient pressure is a pressure higher than the atmospheric pressure.

5. (Amended) The method of fabricating a nitride semiconductor device of claim 4, wherein said second nitride semiconductor layer includes indium.

RECEIVED  
JUN 19 2002  
10 2600 MAIL ROOM

B1  
cont